

1 **Supplementary information for programmable mixed-kernel**
2 **based on MoTe₂/MoS₂ heterojunction for support vector machine**
3 **learning**

4 Xinyu Huang^{1, *}, Jiapeng Du^{1, *}, Langlang Xu^{1, *}, Lei Tong^{2, †}, Xiangxiang Yu^{1, †},
5 Lei Ye^{1, 3, †}

6 ¹ School of Integrated Circuits, Wuhan National Laboratory for Optoelectronics, Huazhong University
7 of Science and Technology, Wuhan, China

8 ² Department of Electronic Engineering, Materials Science and Technology Research Center, The
9 Chinese University of Hong Kong, Hong Kong, China

10 ³ Yangtze Laboratory, Wuhan, China

11 * These authors contributed equally to this work.

12 † Corresponding authors. Email: leiye@hust.edu.cn (L. Y.); yuxx518@126.com (X. Y.);
13 leitong@cuhk.edu.hk (L. T.)

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16 **Supplementary notes**

17 **1. Device fabrication.**

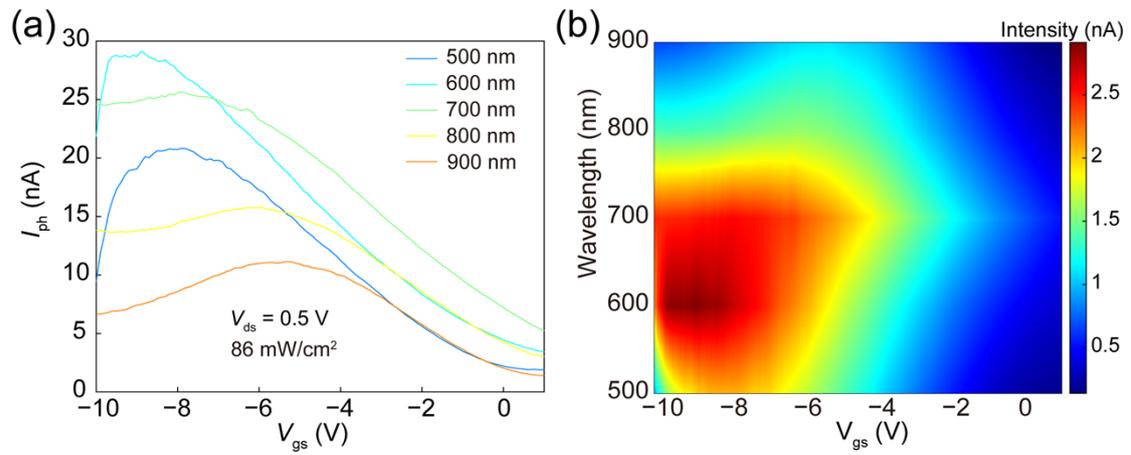
18 Few-layer MoTe₂/MoS₂ flakes were mechanically exfoliated from bulk crystals
19 (from HQ Graphene). Suitable few-layer flakes with uniform surfaces and dimensions
20 near 10 × 20 μm² were identified and selected. These flakes were then precisely
21 assembled into a lateral heterostructure on a substrate using a PDMS-assisted
22 (polydimethylsiloxane) deterministic transfer method. Subsequently, Cr/Au (5/50 nm)
23 source/drain contacts were defined via ultraviolet photolithography and deposited by
24 electron-beam evaporation. Finally, the sample was mounted and wire-bonded onto a
25 24-pin chip carrier.

26 **2. Experimental setup.**

27 For optoelectronic measurements, quasi-monochromatic light was generated by
28 passing a continuous-wave (CW) laser beam (Changjiang Soton, Model: SC-PRO)
29 through a controller-driven monochromator. The light was then focused onto the device
30 via a 10× microscope objective. A commercial spectrometer (Ocean Optics, HR-
31 4VN400-5) was used to measure the reference spectrum information. The gate voltage
32 was applied using a source measure unit (National Instruments, PXIe-4141/4142),
33 which simultaneously recorded the output current. Standard electrical characterization
34 was conducted using a semiconductor device analyzer (Keysight B1500A) integrated
35 with a Lake Shore probe station. All measurements were performed at room
36 temperature under ambient conditions.

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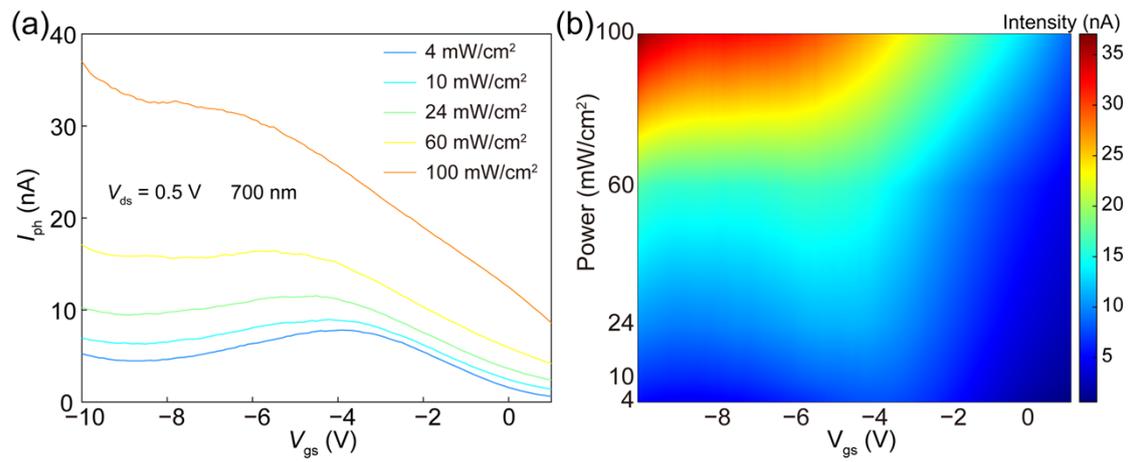
38 **Supplementary figures**



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40 **Fig. S1. (a)** Photocurrent as a function of gate voltage under illumination at a fixed
41 power density of 86 mW/cm² for various wavelengths. **(b)** 2D pseudocolor plot of the
42 photocurrent at 46 mW/cm² as a function of gate voltage and wavelength, visualizing
43 the systematic evolution of the photocurrent peak.

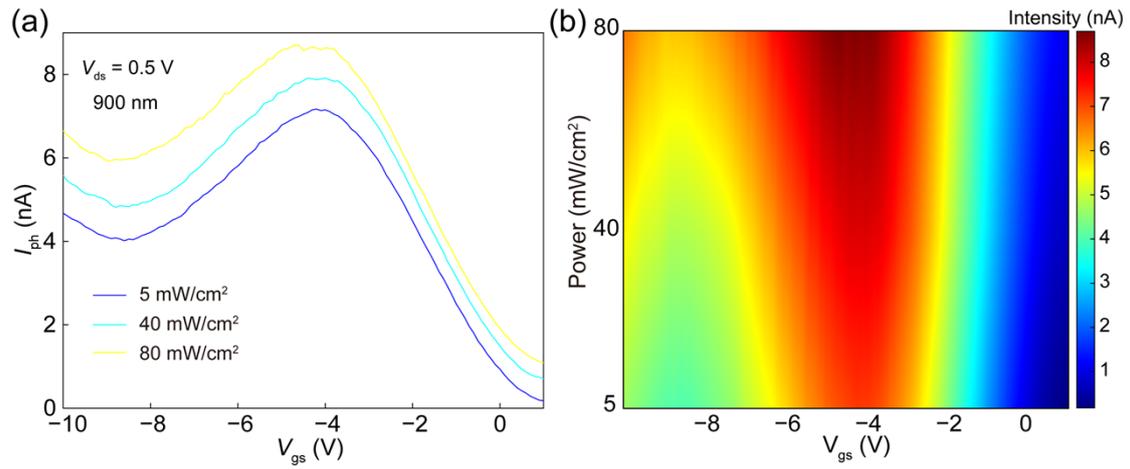
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46 **Fig. S2. (a)** Photocurrent as a function of gate voltage under illumination at a fixed
 47 wavelength of 700 nm for various optical power densities. **(b)** 2D pseudocolor plot of
 48 the photocurrent at 700 nm as a function of gate voltage and optical power, visualizing
 49 the systematic evolution of the photocurrent peak.

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52 **Fig. S3. (a)** Photocurrent as a function of gate voltage under illumination at a fixed
 53 wavelength of 900 nm for various optical power densities. **(b)** 2D pseudocolor plot of
 54 the photocurrent at 900 nm as a function of gate voltage and optical power, visualizing
 55 the systematic evolution of the photocurrent peak.

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